

Didier Theron

List of Publications by Year in descending order

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26
papers

642
citations

1039880

9
h-index

839398

18
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26
all docs

26
docs citations

26
times ranked

789
citing authors

#	ARTICLE	IF	CITATIONS
1	Near-Field Scanning Millimeter-Wave Microscope Operating Inside a Scanning Electron Microscope: Towards Quantitative Electrical Nanocharacterization. Applied Sciences (Switzerland), 2021, 11, 2788.	1.3	2
2	Electric circuit model of microwave optomechanics. Journal of Applied Physics, 2021, 129, 114502.	1.1	8
3	Exploring the Capabilities of Scanning Microwave Microscopy to Characterize Semiconducting Polymers. Applied Sciences (Switzerland), 2020, 10, 8234.	1.3	0
4	Nanoscale Studies at the Early Stage of Water-Induced Degradation of $\text{CH}_3\text{NH}_3\text{PbI}_3$ Perovskite Films Used for Photovoltaic Applications. ACS Applied Nano Materials, 2020, 3, 8268-8277.	2.4	5
5	Multimodal imaging technology by integrated scanning electron, force, and microwave microscopy and its application to study microscaled capacitors. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2018, 36, 022901.	0.6	6
6	Gallium nitride MEMS resonators: how residual stress impacts design and performances. Microsystem Technologies, 2018, 24, 371-377.	1.2	8
7	Quantitative Error Analysis in Near-Field Scanning Microwave Microscopy. , 2018, , .		1
8	Improved analytical modelling and finite element verification of stressed GaN microbeam resonators by piezoelectric actuation. Journal of Micromechanics and Microengineering, 2017, 27, 095001.	1.5	2
9	Near-field scanning millimeter-wave microscope combined with a scanning electron microscope. , 2017, , .		1
10	Multi-MHz micro-electro-mechanical sensors for atomic force microscopy. Ultramicroscopy, 2017, 175, 46-57.	0.8	8
11	Sensitivity and accuracy analysis in scanning microwave microscopy. , 2016, , .		12
12	Gallium nitride MEMS resonators: How residual stress impacts design and performances. , 2016, , .		1
13	High speed e-beam lithography for gold nanoarray fabrication and use in nanotechnology. Beilstein Journal of Nanotechnology, 2014, 5, 1918-1925.	1.5	21
14	Quantitative impedance characterization of sub-10 nm scale capacitors and tunnel junctions with an interferometric scanning microwave microscope. Nanotechnology, 2014, 25, 405703.	1.3	22
15	Gallium Nitride as an Electromechanical Material. Journal of Microelectromechanical Systems, 2014, 23, 1252-1271.	1.7	173
16	Near-field microscopy: Is there an alternative to micro and nano resonating cantilevers?. , 2014, , .		2
17	Measurement Techniques for RF Nanoelectronic Devices: New Equipment to Overcome the Problems of Impedance and Scale Mismatch. IEEE Microwave Magazine, 2014, 15, 30-39.	0.7	49
18	Young's modulus extraction of epitaxial heterostructure AlGaIn/GaN for MEMS application. Physica Status Solidi (A) Applications and Materials Science, 2014, 211, 1655-1659.	0.8	14

#	ARTICLE	IF	CITATIONS
19	Bias Dependence of Gallium Nitride Micro-Electro-Mechanical Systems Actuation Using a Two-Dimensional Electron Gas. Applied Physics Express, 2012, 5, 067201.	1.1	7
20	Electromechanical Transconductance Properties of a GaN MEMS Resonator With Fully Integrated HEMT Transducers. Journal of Microelectromechanical Systems, 2012, 21, 370-378.	1.7	82
21	Field Effect Transistors for Terahertz Detection and Emission. Journal of Infrared, Millimeter, and Terahertz Waves, 2011, 32, 618-628.	1.2	40
22	attoF MOS varactor RF measurement VNA coupled with interferometer. , 2011, , .		2
23	GaN: A multifunctional material enabling MEMS resonators based on amplified piezoelectric detection. , 2011, , .		5
24	Amplified piezoelectric transduction of nanoscale motion in gallium nitride electromechanical resonators. Applied Physics Letters, 2009, 94, .	1.5	110
25	12 GHz f_{MAX} GaN/AlN/AlGaIn Nanowire MISFET. IEEE Electron Device Letters, 2009, 30, 322-324.	2.2	55
26	Nonlinear Characterization and Modeling of Carbon Nanotube Field-Effect Transistors. IEEE Transactions on Microwave Theory and Techniques, 2008, 56, 1505-1510.	2.9	6